

ELECTRONIC INFORMATION DISCLOSURE STATEMENT

Electronic Version v18

Stylesheet Version v18.0

Title of
Invention

METHOD OF FORMING SILICON-ON-INSULATOR
WAFERS HAVING PROCESS RESISTANT APPLICATIONS

Application Number: 10/604146

Confirmation Number: 6/27/03







First Named Applicant: Joel DeSouza

Attorney Docket Number: FIS920030091

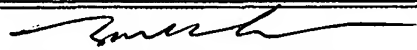
Search string: (5352341 or 5468657 or 5989981 or 6090689 or 6222253 or 6417078).pn.

US Patent Documents

Note: Applicant is not required to submit a paper copy of cited US Patent Documents

init	Cite.No.	Patent No.	Date	Patentee	Kind	Class	Subclass
	1	5352341	1994-10-04	Joyner			
	2	5468657	1995-11-21	Hsu			
	3	5989981	1999-11-23	Nakashima et al.			
	4	6090689	2000-07-18	Sadana et al.			
	5	6222253	2001-04-24	Sadana et al.			
	6	6417078	2002-07-09	Dolan et al.			

Signature

Examiner Name	Date
	2/4/05